

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Sylvia H. Pas Examiner: TBD  
Serial No: TBD Art Unit: TBD  
Filed: 01/11/01 Docket No.: TI-22398  
For: SYSTEM AND METHOD FOR INTEGRATED OXIDE REMOVAL AND  
PROCESSING OF A SEMICONDUCTOR WAFER

## PRELIMINARY AMENDMENT

January 11, 2001

Assistant Commissioner for Patents  
Washington, DC 20231

Dear Sir:

Please amend the above referenced application as follows:

### In the Specification:

Page 1, before line 1, insert -- This application claims priority under 35 USC § 119(e)(1) of provisional application numbers 60/178,647 filed 01/28/00. --